

PATENT

Atty Docket No.: 200315473-1

App. Ser. No.: 10/697,974

IN THE CLAIMS:

Please find below a listing of all of the pending claims. The statuses of the claims are set forth in parentheses.

1. (Currently amended) A system for delivering material onto a substrate, said system comprising:

a jetting assembly configured to deliver the material to the substrate as droplets;
comprising:

~~a reservoir containing the material, said reservoir having a nozzle through which the material is expelled from the reservoir;~~

~~an arcuate section positioned between the reservoir and the nozzle, wherein the material is configured to travel from the reservoir, through the arcuate section, and through the nozzle;~~

~~a means for applying pressure on the material contained in the reservoir;~~
~~wherein the material is expelled from the reservoir through application of pressure by the means for applying pressure to thereby create a column of the material from the nozzle; and~~

~~a means for producing pressure modulations located proximate the nozzle, the means for producing pressure modulations being configured to substantially regulate formation of droplets from the column of the material;~~

a charging ring, wherein said droplets are configured to pass through the charging ring, and wherein the charging ring is configured to induce an electrical charge to selective ones of the droplets; ~~[[and]]~~

one or more deflection plates for altering a trajectory of the charged droplets;

a support plate configured to support the substrate; and

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an electrostatic potential delivery device for delivering electrostatic potential to the support plate, wherein delivery of electrostatic potential to the support plate operates to vary the velocities at which the droplets impact the substrate.

2 (Currently amended) The system according to claim 1, wherein said support

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